FORM PTO 1449 (modified) ATTY DOCKET NO. 00684.00152.13 APPLICATION NO. Divisional of Appln. No. 09/819,488, filed U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE March 19, 2001 LIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary) APPLICANT Akiyoshi SUZUKI et al. October 17, 2003 FILING DATE October 17, 2003 **GROUP 2852** U.S. PATENT DOCUMENTS FILING DATE \*EXAMINER INITIAL DOCUMENT NUMBER DATE NAME CLASS SUBCLASS FB 04/24/1973 350 US-3,729,252 Nelson 162 SF FSB 12/04/1973 Frosch et al. 355 US-3,776,633 132 FSB US-3,887,816 06/03/1975 Colley 350 571 **\$48** 01/29/1985 362 268 Konno et al. US-4.497.015 ILB. 02/12/1985 **Uehara** 350 523 US-4,498,742 38B US-4,521,082 06/04/1985 Suzuki et al. 350 405 \$HB US-4.619.508 10/28/1986 Shibuya et al. 353 122 #B US-4,634,240 01/06/1987 Suzuki et al. 350 508 FOREIGN PATENT DOCUMENTS **TRANSLATION** DOCUMENT DATE COUNTRY CLASS SUBCLASS YES/NO/ OR ABSTRACT NUMBER ISB 61-91662 05/09/1986 Japan Abstract SHB 0 346 844 06/13/1989 **Europe \$88** 0 293 643 05/10/1988 **Europe** FFB 0 437 376 01/11/1991 **Europe** 0 486 316 11/15/1991 **Europe** OTHER DOCUMENT(S) (Including Author, Title, Data, Pertinent Pages, Etc.) Pol, Victor, et al. "Excimer Laser Based Lithography: A Deep-Ultraviolet Wafer Stepper for VLSI Processing," Optical Engineering, Vol. 26, No. 4, pp. 311-318, April 1987. Yang, S.T., et al. "Effect of Central Obscuration on Image Formation in Projection Lithography," SPIE Vol. 1264 Optical/Laser Microlithography III, pp. 477-485, 1990. H cht-Zajac, Optics, 1st Edition, p. 117, 1974. 33B EXAMINER ... DATE CONSIDERED Opril 2, 2004 Fred & Brown

<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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:FB	US-4,668,077	05/26/1987	Tanaka	355	30		
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358B	US-4,851,882	07/25/1989	Takahashi et al.	355	46		
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FEB	US-4,931,830	06/05/1990	Suwa et al.	355	71		
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FIB	39 33 308 A1	05/03/1990	Germany			No	
75B	28 35 363 A1	03/13/1980	Germany			No	
FSB	40 07 069 A1	09/20/1990	Germany			No	
:35B	61-210627	09/18/1986	Japan			Abstract	
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
FSB	Intl. Cl., 5 <sup>th</sup> Edition	<u>Intl. Cl.</u> , 5 <sup>th</sup> Edition, Vol. 7, Section G, pp. 68 and 72, 1989.					
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\$\$B	Europ an S arch I	Europ an S arch R port r garding 97200014.5 dated May 20, 1997.					
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Fied & Brown			'april 2,5004				

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